



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

First Named
Inventor : Benjamin Y.H. Liu et al.

Appln. No. : 10/769,011

Filed : January 30, 2004

For : HIGH-PERFORMANCE AND MULTI-
LIQUID-PRECURSOR
VAPORIZATION IN
SEMICONDUCTOR THIN FILM
DEPOSITION

Docket No.: M419.12-0043

Group Art Unit: 1763

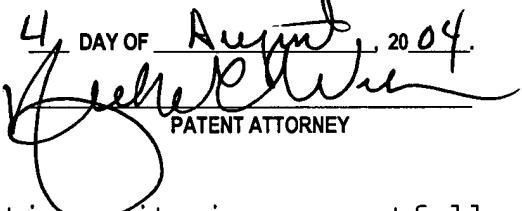
Examiner:

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to the first Official Action, it is respectfully
requested that the following amendments be made.

I HEREBY CERTIFY THAT THIS PAPER IS BEING
SENT BY U.S. MAIL, FIRST CLASS, TO THE
COMMISSIONER FOR PATENTS, P.O. BOX 1450,
ALEXANDRIA, VA 22313-1450, THIS

4 DAY OF August, 2004.

PATENT ATTORNEY